



description

The microCMA (Cylindrical Mirror Analyzer) represents the latest advancement in Auger Electron Spectroscopy. Compact and affordable, the microCMA opens up a whole new world of AES applications, from in-situ analysis on MBE systems to in-line analysis of semiconductors.

benefits

Compact: Fits on a 2.75" (70 mm) flange.

Proven Design: The second order focusing of the CMA provides superior transmission and resolution.

Easy to Use: With a USB interface and an ASCII based command structure, the control and data message software interface is as simple to use as an RGA – point and click.

Powerful: Auger Electron Spectroscopy is a powerful surface-sensitive technique that provides quantitative information on the first few monolayers of your sample.

applications

Analysis of:

- Thin film composition
- Passive oxide thicknesses in semiconductors and metals
- Metal component thermal oxides
- Integrated circuit contamination

Additional applications:

- Characterization of sputtered layers
- Auger depth profiles of deposited layers
- Quantization of light element surface films

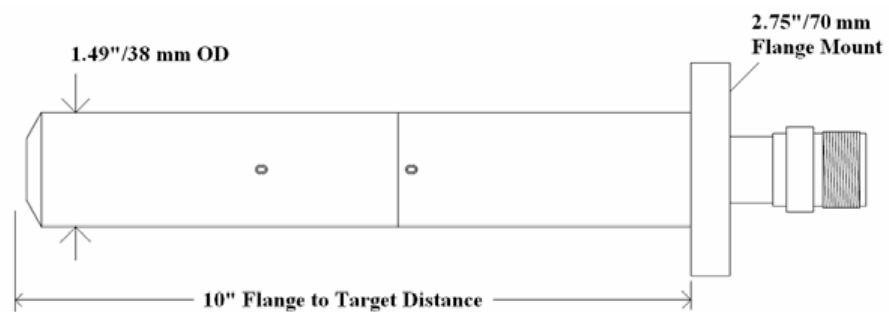
compact Auger analyzer

microCMA

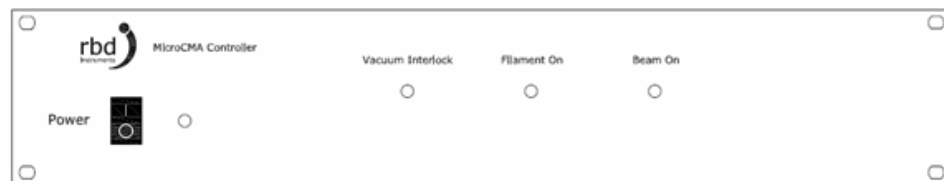
specifications

Analyzer Type	Single Pass CMA (Cylindrical Mirror Analyzer)
Analyzer Working Distance	3 mm (0.12")
Energy Resolution	Fixed at 0.65 %
Signal-to-Noise	1500:1 @ 3 kV 5 μ A on clean copper
Electron Multiplier	Extended Dynamic Range Channelltron
Electron Gun	Coaxial 3 kV, non-imaging
Minimum Spot Size	25 μ m, de-focused 1 mm
Filament	CeBix™
Analyzer Mounting	70 mm (2.75")
Vacuum Integrity	UHV bakeable to 200 degrees C
Power Supply/Control	USB protocol, software controlled

Analyzer:



Control:



Dimensions 3.5" High X 19" Wide X 12" Deep

All specifications are subject to change without notice.



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